

ORIFICE PLATE AND METHOD OF FORMING ORIFICE PLATE FOR FLUID EJECTION DEVICE

Abstract

A method of forming an orifice plate for a fluid ejection device includes depositing and patterning a mask material on a conductive surface, forming a first layer on the conductive surface, forming a second layer on the first layer, and removing the first layer and the second layer from the conductive surface, wherein the first layer includes a metallic material and the second layer includes a polymer material.